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In re application of: Sujit Sharan and Gurtej S. Sandhu

Serial No.: 09/825,613

Filed: April 3, 2001

For: METHOD FOR PECVD DEPOSITION OF SELECTED MATERIAL FILMS

§ Group Art Unit: 2829
§ Examiner: Lisa A Kilday
§ Atty. Docket: 95-0716.03
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FIRST AMENDMENT AND RESPONSE TO THE OFFICE ACTION OF MARCH 7, 2002

Commissioner for Patents
Washington, D.C. 20231

Certificate of Mailing (37 C.F.R. § 1.8)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on the date below:

6/6/02
Date

Susan Jerome
Signature

Dear Sir:

Applicants herein respond to the Office Action of March 7, 2002. Please amend the above-captioned application as follows.

IN THE SPECIFICATION:

Please amend the following Specification paragraphs to the form described below.

[0000] This application is a continuation of application serial number 09/249,478, filed Feb. 12, 1999 and issued as U.S. Pat. No. 6,291,341.

[0027] For the purposes of describing one particular embodiment of the invention, it is assumed that a deposition process is to be carried out within the PECVD system 10 described in